

Annual Meeting of the Swiss Physical Society 2024



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Type: **Talk**

【60】 Making dirt shine - contamination analysis for semiconductor manufacturing

Wednesday 11 September 2024 18:00 (20 minutes)

As semiconductor feature sizes decrease, controlling contamination in manufacturing processes becomes increasingly important. UNISERS builds tools for contamination detection and classification using a unique combination of optical microscopy and Raman spectroscopy, quantifying contaminants on wafers and in liquids. This talk highlights our techniques and their applications, while giving insight into a workplace for physicists at the intersection of fundamental physics, data science, and product development.

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Session Classification: Startups: The role of physics and physicists in developing a product ?

Track Classification: Startups: The role of physics and physicists in developing a product?